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Dated: December 18, 2008 Signature

EXPEDITED PROCEDURE Art unit 2822

Docket No.: 29936/39764

(PATENT)

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Jennifer Lape

In re Patent Application of: Cha Deok Dong

Application No.: 10/720,457

Filed: November 24, 2003

For: Method for Forming Device Isolation Film in

Semiconductor Device

Confirmation No.: 4077

Art Unit: 2822

Examiner: M. M. Trinh

AMENDMENT AFTER FINAL ACTION UNDER 37 C.F.R. 1.116

MS AF Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

Dear Sir:

INTRODUCTORY COMMENTS

In response to the official action dated October 18, 2006, finally rejecting claims 1-14, please amend the above-identified U.S. patent application as follows:

Amendments to the Claims are reflected in the listing of claims which begins on page 2 of this paper.

Remarks/Arguments begin on page 3 of this paper.

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